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+ 689

****CONTINUING DATA VERIFIED:**
LAK none 6/18/03

****FOREIGN APPLICATIONS VERIFIED:**
LAK none 6/18/03

PG-PUB <input type="checkbox"/>	DO NOT PUBLISH <input type="checkbox"/>	RESCIND <input type="checkbox"/>
Foreign priority claimed 35 USC 119 conditions met Verified and Acknowledged Examiners's initials	<input type="checkbox"/> yes <input checked="" type="checkbox"/> no <input type="checkbox"/> yes <input checked="" type="checkbox"/> no <i>LAK</i>	ATTORNEY DOCKET NO M122-1798

TITLE : Etching processes for integrated circuit manufacturing including methods of forming capacitors

U.S. DEPT. OF COMM./PAT. & TM-PTO-436 (Rev. 12-94)

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